IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application.

1. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition from [[the]] below toward an anode or a cathode <u>facing downward</u> under a pressure lower than atmosphere pressure; and forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

2. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition from [[the]] below toward an anode or a cathode <u>facing downward</u> under a pressure of 1×10^2 to 1×10^5 Pa; and

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

3. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition from [[the]] below toward an anode or a cathode <u>facing downward</u> under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode and volatilizing a

solvent in the solution in a duration before the solution arrives at the anode or the cathode.

4. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of: ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

5. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of: ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode at from room temperature to 200 °C; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

6. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

setting up an anode or a cathode <u>facing downward</u> in a range of 0° to 30° relative to a horizontal plane;

ejecting a solution containing a light-emitting body composition from [[the]] below under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

7. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

setting up an anode or a cathode <u>facing downward</u> in a range of 0° to 30° relative to a horizontal plane;

ejecting a solution containing a light-emitting body composition from [[the]] below under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate.

8. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of: setting up an anode or a cathode in a range of 0° to 30° relative to a horizontal plane; ejecting a solution containing a light-emitting body composition from the below under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

9. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of: setting up an anode or a cathode in a range of 0° to 30° relative to a horizontal plane; ejecting a solution containing a light-emitting body composition from the below under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode at from room temperature to 200 °C; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

10. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode provided on a substrate <u>facing downward</u> under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the film of the light-emitting body composition,

wherein the fabrication method of the light-emitting device is further characterized in that the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

11. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode <u>facing</u> <u>downward</u> under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

12. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of: ejecting a solution containing a light-emitting body composition toward an anode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method

after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

13. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of: ejecting a solution containing a light-emitting body composition toward an anode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode at from room temperature to 200 °C;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

14. (Previously Presented) A fabrication method of a light-emitting device according to claims 10 or 11.

wherein each of the formations of the thin film having at least one layer structuring the light-

emitting body and the cathode is performed in a deposition apparatus in a multi-chamber scheme without a release to the air.

15. (Previously Presented) A fabrication method of a light-emitting device according to claims 10 or 11,

wherein each of the formations of the thin film having at least one layer structuring the lightemitting body and the cathode is performed in a deposition apparatus in an in-line scheme without a release to the air.

16. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode provided on a substrate <u>facing downward</u> under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the cathode; and

forming an anode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of a thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

17. (Currently Amended) A fabrication method of a light-emitting device comprising the

steps of:

ejecting a solution containing a light-emitting body composition toward a cathode <u>facing</u> <u>downward</u> under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the cathode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate; and

forming an anode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

18. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of: ejecting a solution containing a light-emitting body composition toward a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the cathode by previously heating the cathode;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the cathode; and

forming an anode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of at the thin film having at least one layer structuring the light-

emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

19. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of: ejecting a solution containing a light-emitting body composition toward a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the cathode by previously heating the cathode at from room temperature to 200 °C;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the cathode; and

forming an anode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

20. (Previously Presented) A fabrication method of a light-emitting device according to claims 16 or 17,

wherein each of the formations of the thin film having at least one layer structuring the lightemitting body and the cathode is performed in a deposition apparatus in a multi-chamber scheme without a release to the air. 21. (Previously Presented) A fabrication method of a light-emitting device according to claims 16 or 17,

wherein each of the formations of the thin film having at least one layer structuring the lightemitting body and the cathode is performed in a deposition apparatus in an in-line scheme without a release to the air.

22. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein under the pressure lower than atmosphere pressure is in an inert gas atmosphere at 1 \times 10³ to 1 \times 10⁵ Pa.

23. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein under the pressure lower than atmosphere pressure is in an inert gas atmosphere at 1 \times 10² to 1 \times 10⁵ Pa.

24. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein the light-emitting body composition is intermittently deposited to form a thin film.

25. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein the light-emitting body composition is continuously deposited to form a thin film.

26. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein the solution containing the light-emitting body composition is ejected through a single or a plurality of nozzles.

27. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein the light-emitting body composition is at least one material selected from the group consisting of a hole injection material, a hole transport material, a luminescent material, an electron transport material, an electron injection material, a hole blocking material and an electron blocking material.

28. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein the thin film having at least one layer structuring the light-emitting body is a thin film to function as a layer selected from a luminescent layer, a hole injection layer, a hole transport layer, a hole blocking layer, an electron injection layer, an electron transport layer and an electron blocking layer.

29. (Previously Presented) An electronic appliance comprising the light-emitting device fabricated by a method according to any one of claims 1, 3, 6-7, 10-11, 16-17.